# INFORMATION DISCLOSURE STATEMENT BY APPLICANT

Application No. 10/826,219 .

Filing Date April 16, 2004

First Named Inventor Homayoun Talieh

Art Unit 1742

Examiner Unknown

Multiple sheets used when necessary)

SHEET 1 OF 3 Attorney Docket No. ASMNUT.037C5

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Examiner Signature /Lois Zheng/ Date Considered 03/19/2007

\*Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

T<sup>1</sup> - Place a check mark in this area when an English language Translation is attached.

#### Application No. 10/826,219 INFORMATION DISCLOSURE Filing Date April 16, 2004 First Named Inventor Homayoun Talieh STATEMENT BY APPLICANT Art Unit 1742 (Multiple sheets used when necessary) Examiner Unknown SHEET 2 OF 3 Attorney Docket No. ASMNUT.037C5

U.S. PATENT DOCUMENTS								
Examiner Initials		Cite No.		Document Number	Publication Date	Name of Patentee or Applicant	Pages, Columns, Lines Where Relevant Passages or Relevant Figures Appear	
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Examiner Initials	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>1</sup>				
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Examiner Signature	/Lois Zheng/	Date Considered	03/19/2007

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PTO/SB/08 Equivalent

-	Application No.	10/826,219
INFORMATION DISCLOSURE	Filing Date	April 16, 2004
STATEMENT BY APPLICANT	First Named Inventor	Homayoun Talieh
STATEMENT BY AFFEICANT	Art Unit	1742
(Multiple sheets used when necessary)	Examiner	Unknown
SHEET 3 OF 3	Attorney Docket No.	ASMNUT.037C5

	NON PATENT LITERATURE DOCUMENTS					
Examiner Initials	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T¹			
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Examiner Signature /Lois Zheng/ Date Considered 03/19/2007

<sup>\*</sup>Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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# IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Group Art Unit: Not yet assigned

Talieh et al.

Examiner: Not yet assigned Docket: NT-105C5-US

Serial No.: 10/459,321

Filed: June 10, 2002

Title: Device Providing Electrical Contact To The Surface Of A Semiconductor Workpiece

**During Processing** 

### INFORMATION DISCLOSURE STATEMENT

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Initials	No.			lation
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/LZ/	·	James J. Kelly et al., "Leveling and Microstructural Effects of Additives for Copper Electrodeposition", Journal of Electrochemical Society, 146 (7), 1999, Pages 2540-2545	In related S/N 09/685,934	
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